

IN THE CLAIMS:

Please amend the claims as follows:

Claim 1. (Currently Amended): An organic EL device comprising:
a lower electrode formed on a substrate;
an organic EL layer formed on the lower electrode;
an upper electrode formed on the organic EL layer;
a sealing member for sealing said lower electrode, organic EL layer and upper electrode
on said substrate so that they are covered with the sealing member, wherein said sealing member
is further comprised of an aluminum material and is coated **by anodic oxidation** with an
absorbing material made of a porous aluminum oxide.

Claim 2. (Original): An organic EL device according to claim 1, wherein said aluminum
material is a flexible aluminum sheet.

Claim 3. (Cancelled)

Claim 4. (Cancelled)

Claim 5. (Currently Amended): An organic EL device according to claim 1, wherein
said aluminum sheet is formed in such a manner that a surface of said aluminum oxide layer is

subjected to gas flow-out treatment in vacuum such that the pores of the surface of the aluminum oxide layer are substantially free of gases, and thereafter said lower electrode, organic EL layer and upper electrode are sealed on the substrate in an atmosphere of inert gas.

Claims 6. (Withdrawn) : A method of manufacturing an organic EL device comprising the steps of:

- forming a lower electrode formed on a substrate;
- forming an organic EL layer on the lower electrode;
- forming an upper electrode on the organic EL layer to provide the organic EL device;
- preparing an aluminum material coated with an insulating layer in at least its inner surface; and
- sealing said organic EL device so that it is covered with said aluminum material.

Claim 7. (Withdrawn): A method of manufacturing an organic EL device according to claim 6, wherein

- said step of preparing the aluminum material comprises the steps of:
 - making anodic oxidation to form an aluminum oxide layer on a surface of a flexible aluminum sheet; and
 - removing gas contained within said aluminum oxide layer, and
- said step of sealing said organic EL device comprises the step of:

fixing said aluminum sheet with the gas removed on a surface of said substrate in an atmosphere of inert gas or in vacuum.

Claim 8. (Withdrawn): A method of manufacturing an organic EL device according to claim 1, wherein said step of removing gas is to heat the aluminum sheet with the aluminum oxide layer for several-60 minutes at 60-300 °C in vacuum.

Claim 9. (Withdrawn): A method of manufacturing an organic EL device according to claim 7, wherein said step of making anodic oxidation is to form a porous aluminum oxide layer; and

said step of removing gas is to heat said aluminum sheet in vacuum so that impurities contained in pores of said porous aluminum oxide layer are discharged.

Claim 10. (Withdrawn): A method of manufacturing an organic EL device according to claim 7, wherein

said step of sealing said organic EL device comprises the steps of:

mounting said organic EL device and aluminum sheet in a sealing chamber and once heating them at room temperature- 150 °C in vacuum;

introducing inert gas into the sealing chamber; and

fixing said aluminum sheet to said substrate through an adhesive and heating it.

Claim 11. (Withdrawn): A method of manufacturing an organic EL device according to claim 7, wherein said inert gas is argon gas.

Claim 12. (Previously Added): An organic EL device according to claim 1, wherein said sealing member has a thickness of approximately 10 μm .